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INFORMATION DISCLOSURE CITATION				Applicant Ayazi, et al.			
(Use several sheets if necessary)				Filing Date September 23, 2003		Group 2817	
U.S. PATENT DOCUMENTS							
Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A	6,549,099	4-15-03	Taussig	333	186	6-29-01
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	B	WO 02/01717 A1	1/3/02	PCT			Abstract
	C	WO 03/043189 A2		PCT			Abstract
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	D	Galayko, D., Kaiser, A., Buchailot, L. et al. (2003) Microelectromechanical Variable-Bandwidth IF Frequency Filters With Tunable Electrostatic Coupling Spring. IEEE., pp. 153-156					
	E	No, S.Y., Hashimura, A., Pourkamali, S. et al., Single-Crystal Silicon HARPSS Capacitive Resonators with Submicron Gap-Spacing, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA; for proceedings at Hilton Head 2002.					
DT	F	Pourkamali, S., Abdolvand, R., Hashimura, A. et al. HARPSS Single Crystal Silicon Filter Arrays. School of Electrical and Computer Engineering, Georgia Institute of Technology, GA, June 2002.					
	G	Wang, K., Bannon, F.D., Clark, J.R. et al. (1997) Q-Enhancement of Microelectromechanical Filters Via Low-Velocity Spring Coupling., Proceedings, IEEE International Ultrasonics Symposium, Toronto, Canada, Oct. 5-8, 1997, pp. 323-327.					
	H	Wang, K. and Nguyen, T.C. (1997) High-Order Micromechanical Electronic Filters, Proceedings, IEEE International Micro Electro Mechanical Systems Workshop, Nagoya, Japan, Jan. 26-30, 1997, pp. 25-30.					
	I	Pourkamali, et al. A 600kHz Electrically-Coupled MEMS Bandpass Filter, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA, MEMS 2003 Conference, Kyoto Japan, Jan. 19-23, 2003.					
	J	Pourkamali, et al. Electrostatically Coupled Micromechanical Beam Filters, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA, MEMS 2003 Conference, Kyoto, Japan, Jan. 19-23, 2003, Pages 702-705.					
	K	Ayazi, Farrokh, et al., Capacitive Resonators And Methods Of Fabrication, filed with the USPTO on July 31, 2003, having serial no. 10/632,176.					
* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							
EXAMINER'S SIGNATURE: 				DATE CONSIDERED: 2/15/06			
Patent and Trademark Office; U. S. DEPARTMENT OF COMMERCE							

References A - E and G - K are duplicates of the IDS dated 3/12/04 which has been previously considered.